

Abstract

The present invention relates to two new wave field
microscopes, type I and type II, which are distinguished by
the fact that they each have an illumination and excitation
system, which include at least one real and one virtual
illumination source, and at least one objective lens (in the
case of type II), i.e., two objective lenses (in the case of
type I), with the illumination sources and objective lenses
being so positioned with respect to one another that they are
suited for generating one-, two-, and three-dimensional
standing wave fields in the object space. The calibration
method in accordance with the present invention is adapted to
this wave field microscopy and permits geometric distance
measurements between fluorochrome-labeled object structures,
whose distance can be less than the width at half maximum
intensity of the effective point spread function. The
invention relates moreover to a method of wave-field
microscopic DNA sequencing.